



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Tetsuo TANIGUCHI

GAU:

2851

SERIAL NO: 09/618,550

EXAMINER: NGUYEN, H.

FILED:

JULY 17, 2000

FOR:

TECHNOLOGY CENTER 2001 EXPOSURE METHOD AND LITHOGRAPHY SYSTEM, EXPOSURE APPARATUS AND METHOD OF

MAKING THE APPARATUS, AND METHOD OF MANUFACTURING DEVICE

REQUEST FOR EXTENSION OF TIME **UNDER 37 C.F.R. 1.136**

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

It is hereby requested that a two month extension of time be granted to AUGUST 21, 2002 for

- filing a response to the Official Action dated: MARCH 21, 2002
- responding to the requirements in the Notice of Allowability dated:
- filing the Formal Drawings. The Issue Fee due

has been timely filed.

- responding to the Notice to File Missing Parts of Application dated:
- ☐ filing a Notice of Appeal. A timely response to the final rejection, due

has been filed.

lorlar

- ☐ filing an Appeal Brief. A Notice of Appeal was filed on:
- ☐ Applicant claims small entity status. See 37 CFR 1.27. Therefore, the fee amount shown below is reduced by one-half.

The required fee of \$400.00 is enclosed herewith by check and any further charges may be made against the Attorney of Record's Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

08/22/2002 SZEWDIE1 00000005 09618550

01 FC:116

400.00 OP



Tel. (703) 413-3000 Fax. (703) 413-2220 (OSMMN 11/98)

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

Gregory J. Maier

Registration No. 25,599

David A. Bilodeau

42,325 Registration No.